



PROPERTIES OF IRON SILICIDES IN SINGLE-CRYSTAL SILICON

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Abstract

This paper presents the properties of iron silicide compounds in n-type silicon. The iron layer was formed with a thickness of $1 \div 2 \mu\text{m}$ by magnetron sputtering onto the surface of silicon grown by the n-type Czochralski method in an atmosphere of pure inert argon gas. The properties of iron silicide and the formation of complexes of iron silicides in the volume of silicon have been studied.

Keywords: silicides, morphology, vacancy, spectrum, temperature, diffusion, composition, surface.

Introduction

Iron is one of the most common and harmful metal impurities in silicon. Generation-recombination centers associated with dissolved iron and its complexes increase leakage currents in any reverse biased junction, which increases energy consumption and heat generation. In crystalline and polycrystalline photovoltaic devices, iron contamination leads to the creation of recombination centers that reduce the diffusion length of minority charge carriers and hence the efficiency of the solar cell [1]. As device sizes continue to shrink, device performance becomes more susceptible to defects and contamination [2,3]. Since ultrapure technology to reduce surface iron contamination to below 10^{10} – 10^{11} cm^{-2} is extremely expensive, understanding the mechanisms of iron contamination, the detrimental role of iron in silicon devices, and the allowable limits of iron contamination for each specific process is becoming increasingly important. This requirement aroused great interest in the physics of iron in silicon.

The main obstacle in establishing a consistent experimental picture of 3d - transition metals in silicon and, in particular, iron, arises from the high diffusivity of these elements. Iron remains mobile at room temperature and can diffuse rapidly at temperatures above 100 °C. Because interstitial iron is positively charged in p-Si at





room and slightly elevated temperatures, it readily pairs with negatively charged defects such as shallow acceptors. The diffusion coefficients of transition metals in silicon depend on the charge state of the metal, since the ionic radii of neutral and ionized particles are different, as well as the degree of overlap of the electron density of diffusing atoms with the surrounding silicon matrix. The migration enthalpies and preexponential factors of the largest of the 3d ions can be calculated with amazing accuracy as the difference in elastic energies at tetrahedral and hexagonal interstices using the hard sphere model, as proposed by U [4].

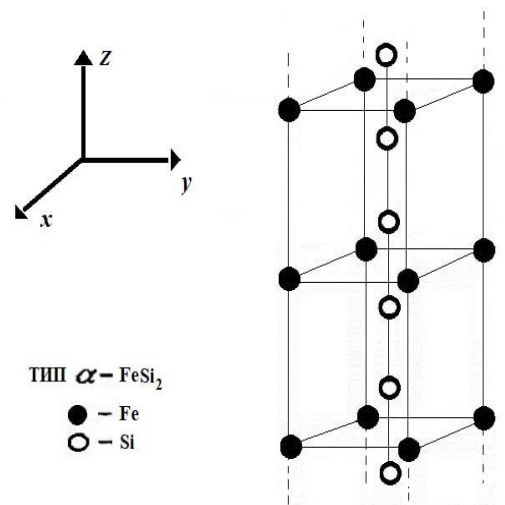


Fig. 1. Compound of iron silicide FeSi₂ have the same cubic crystal structure.

Experiment

Single-crystal silicon samples 0.7x14x15 mm in size with $\rho = 50$ Ohm-cm of n-type with a surface layer of iron were annealed in an electric muffle furnace of the KSI-1075-1 brand in the temperature range of 900-1250 °C for 10-12 hours. As a source of diffusion, iron was used, deposited by the method of magnetron ion sputtering with a thickness of 1.5-2 μm in an argon atmosphere on cold silicon substrates on the polished surface of a silicon sample with carborundum powder M-14, M-10, M-7.

Fig. 2. shows the surface of silicon before and after the deposition of pure iron by magnetron ion sputtering in an argon atmosphere [5]. Since sputtering is a low-temperature process, it can be used to obtain films of metals (including refractory), alloys (including multicomponent composition), semiconductors and semiconductor compounds.

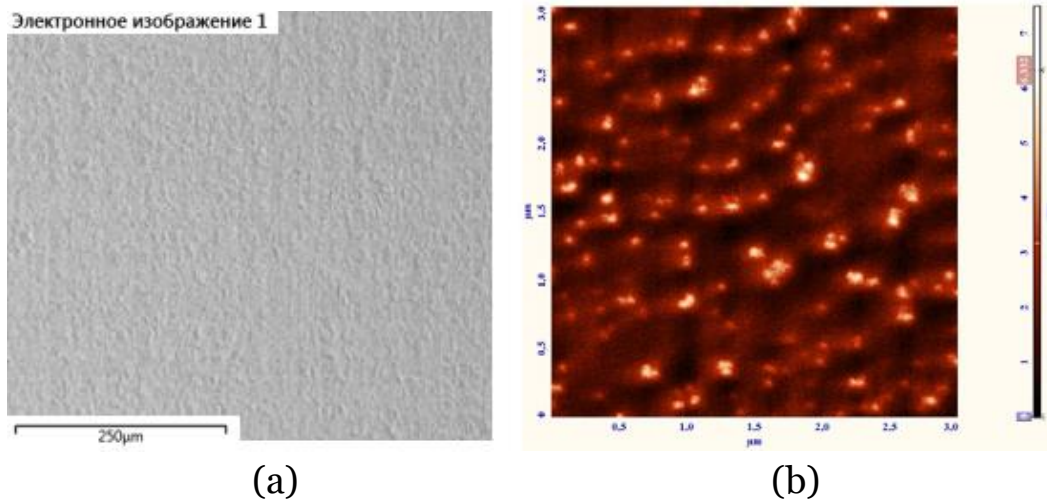


Fig.2. AFM image of the silicon surface before (a) and after the deposition of pure iron (b) by magnetron ion sputtering in an argon atmosphere at room temperature of the substrate.

The Raman spectrometer makes it possible to measure Raman spectra (RS) and combine spatially resolved molecular information with high-quality microscopic images. Using a BRUKER SENTERRA II Raman spectrometer, the elemental composition of the initial single-crystal silicon (Fig. 3) and iron-doped silicon was determined.

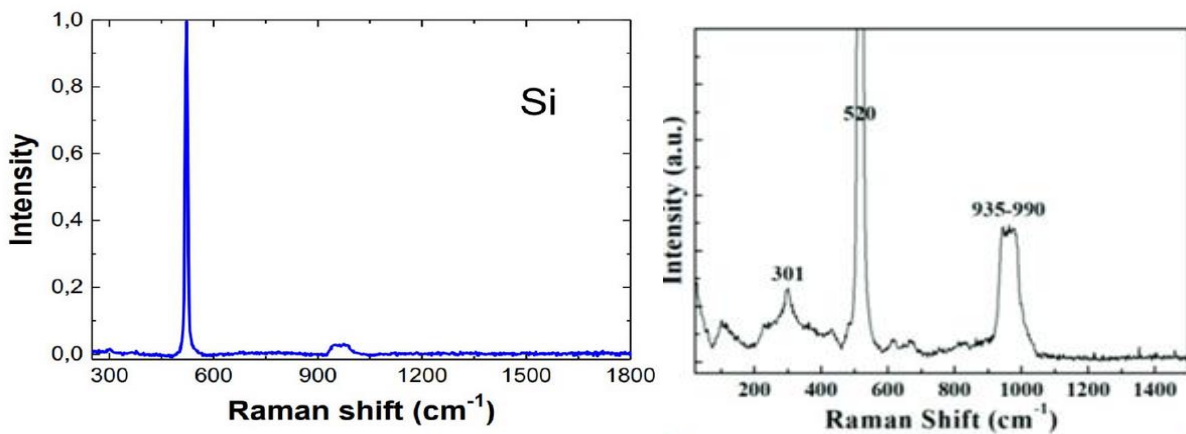


Fig.3. Raman spectrum of original(a) and iron-doped silicon.

Discussion of results. As shown by these studies, on the surfaces of single-crystal silicon of the Si(100)2x1 and Si(111)7x7 orientations, the formation of various non-magnetic silicides is detected at the Si/Fe interface, which worsens the spin injection into silicon. In this case, the formation of films strongly depends on the degree of crystallinity of the surface and its roughness. In addition, the formation processes turn out to be nonidentical for the Si/Fe and Fe/Si interfaces. Understanding this difference is important in the process of creating multilayer films (Fe/Si) n-model



systems for elements of non-volatile memory and sensors. In the "iron-silicon" system, there are a number of stable and metastable phases of iron silicides. The phases stable at room temperature in the case of bulk samples include iron disilicides β -FeSi₂, ε -FeSi, Fe₃Si [4]. The first of them is a direct-gap semiconductor with a band gap of 0.85 eV and is stable up to a temperature of 920°C. Above this temperature, β -FeSi₂ transforms into α -FeSi₂ metal silicide. Monosilicide ε -FeSi is a semimetal (the forbidden energy interval at the Fermi level is 0.05 eV). The Fe₃Si compound, which is the most iron-rich in comparison with other silicides, is a ferromagnetic metal with low conductivity.

Conclusions

The Fe₃Si compound crystallizes in a cubic lattice with a lattice constant of 5.656 Å. Silicide ε -FeSi is formed in a simple cubic lattice B-20 (a=4.488 Å). Silicide α -FeSi₂ has a tetragonal lattice with constants a=9.86 Å, b=7.79 Å, c=5.128 Å. Metastable phases include α -FeSi₂, γ -FeSi₂ and FeSi_{1+x} solid solutions at (0 ≤ x ≤ 1) [3]. Iron disilicide γ -FeSi₂ has a face-centered cubic lattice of the CaF₂ type and with a defect structure of the same type. According to [6], the silicide γ -FeSi₂ has ferromagnetic properties. There are also reports on the preparation of a metastable phase that decomposes into FeSi and Fe₃Si below 825°C [7], such as Fe₅Si₃, in the form of nanowires and nanogranules in a silicon matrix.

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